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## **Novel Applications of the Multi-Beam SEM**

Craig Y. Nakakura

Prepared by  
Sandia National Laboratories  
Albuquerque, New Mexico 87185 and Livermore, California 94550

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# **Novel Applications of the Multi-Beam SEM (U)**

Craig Y. Nakakura, Ph.D.  
Microsystems Assessments

Joseph R. Michael, Ph.D.  
Materials Science & Engineering

Meredith L. Dyck, Ph.D.  
Microsystems Assessments

Jeffrey J. Sniegowski, Ph.D.  
Microsystems Assessments I

Sandia National Laboratories  
P.O. Box 5800  
Albuquerque, New Mexico 87185-MS1248

## **Abstract**

The Zeiss Multi-Beam Scanning Electron Microscope (MultiSEM) was used to image a wide array samples using non-standard operating conditions. The ability of this new, high-throughput imaging technique to produce high-quality images was assessed during this one year LDRD. In addition to exploring new imaging conditions, sample preparation techniques, coupled with theoretical simulations, were explored to optimize the MultiSEM images. To obtain details about the devices imaged, as well as the experimental details, please refer to the classified report from the project manager, Bradley Gabel, or the Cyber IA lead, Justin Ford.

